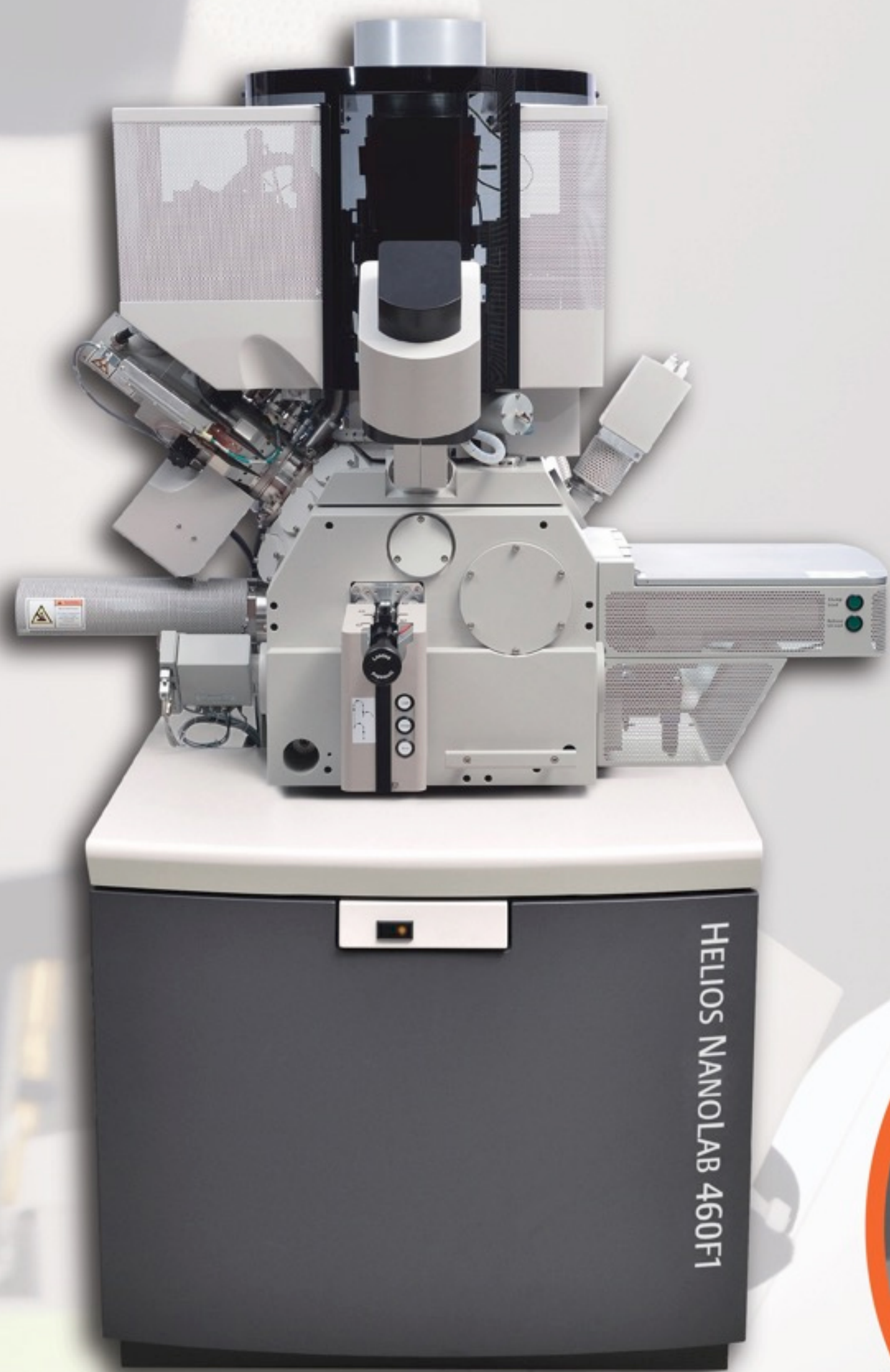
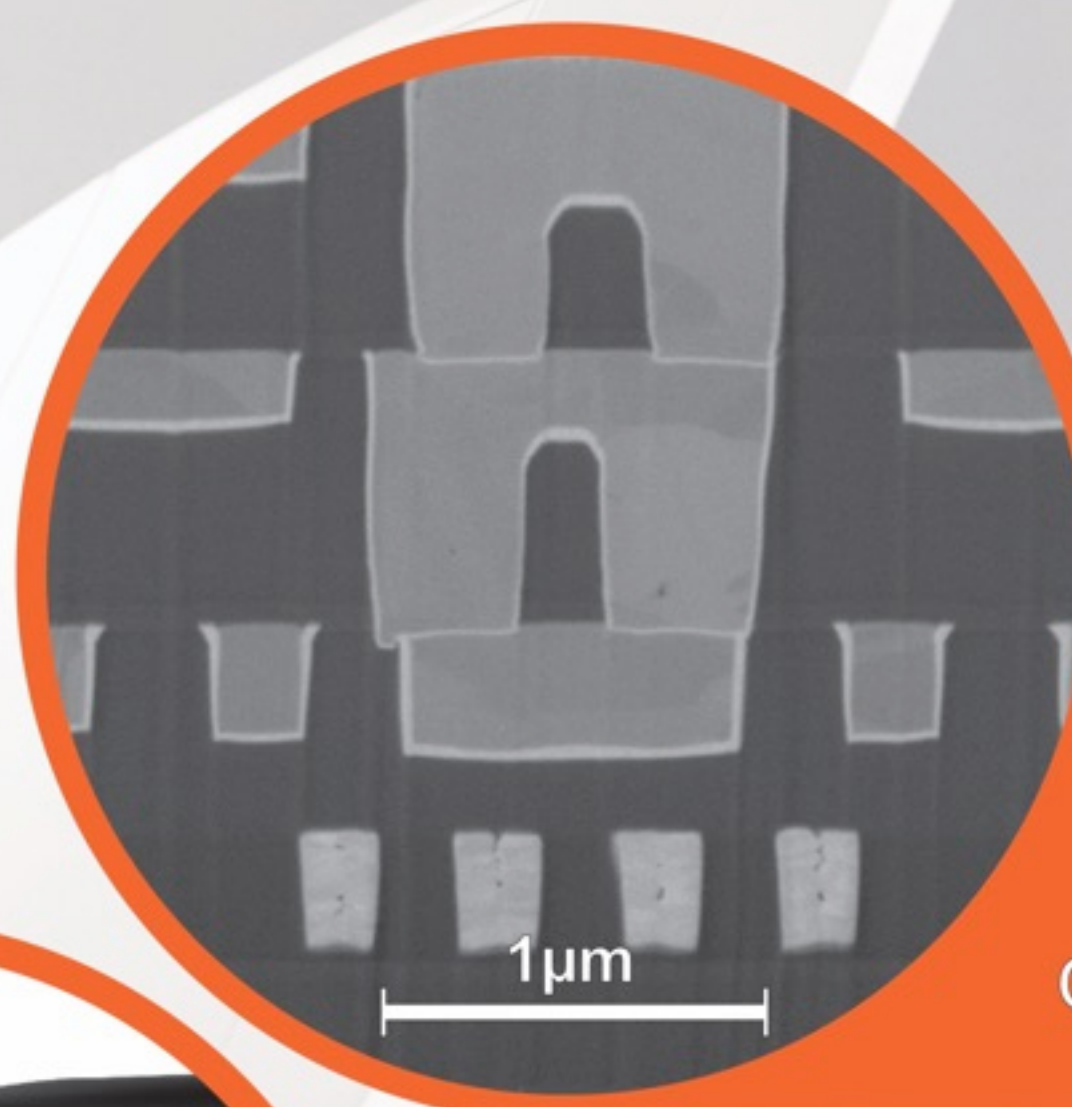


NANOLAB

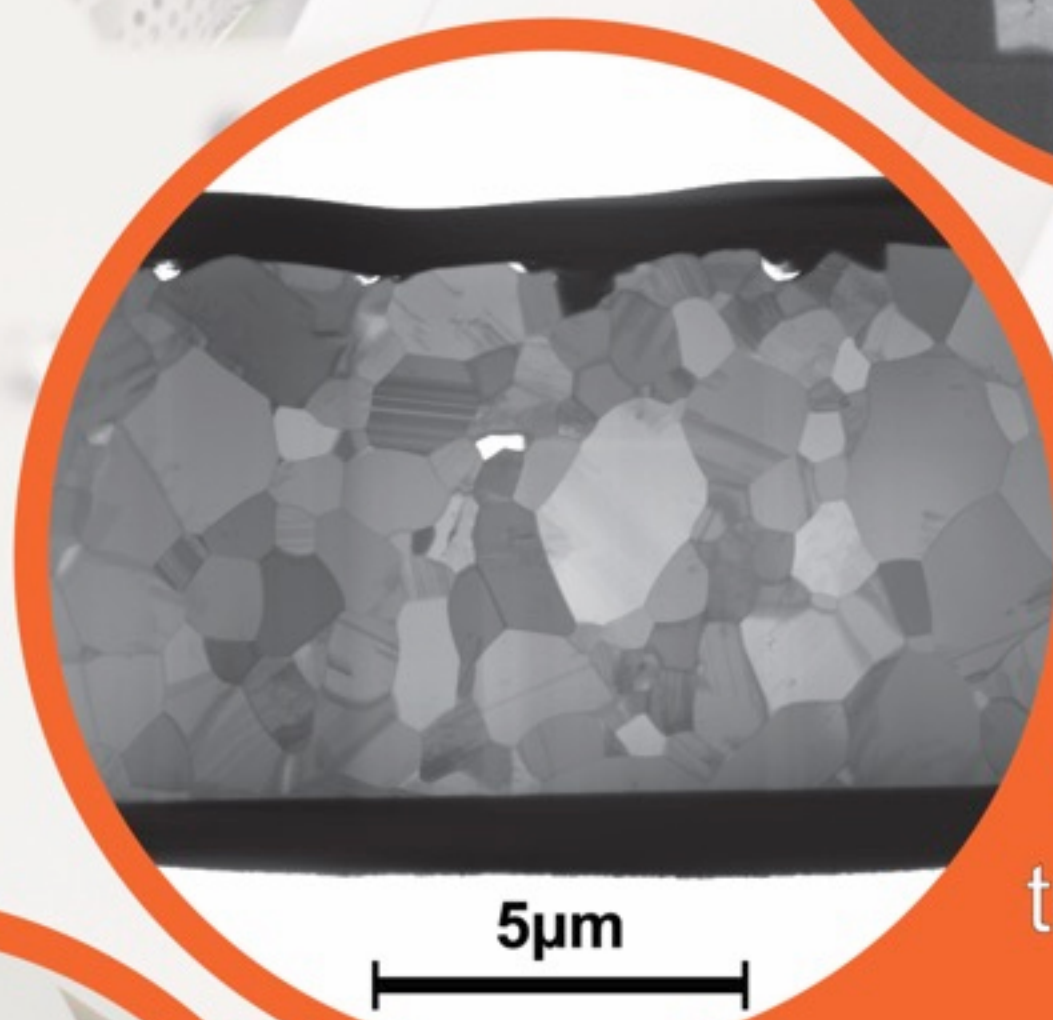
Helios 460F1 Dual Beam



- Dual beam system uses electron beam for imaging and gallium ions for imaging and precise micromachining
- High resolution imaging down to the sub-nanometer level



Cross section by ion beam action of vias in a microcircuit reveals defects in the fabrication.



TEM thin section of polycrystalline ceramic prepared by FIB and imaged in transmission mode in the Helios 460 FIB.



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